

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:

Jon-rok PARK et al.

Application No.: Unassigned

Group Art Unit: Unassigned

Filed: April 9, 2004

Examiner: Unassigned

For: ELECTROSTATIC CHUCK FOR WAFER

**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure provisions of 37 CFR § 1.56, there is hereby provided certain information which the Examiner may consider material to the examination of the subject U.S. patent application. It is requested that the Examiner make this information of record if it is deemed material to the examination of the subject application.

1. Enclosures accompanying this Information Disclosure Statement are:

- 1a. ☒ Form PTO-1449.
- 1b. ☒ Copies of IDS citations.
- 1c. ☐ An English language copy of search report(s) from a counterpart foreign application or a PCT International Search Report.
- 1d. ☒ English language translation (Abstract Only) attached to some of non-English language publications.
- 1e. ☒ Explanations of Relevancy of References (ATTACHMENT 1(e), hereto) for providing a concise explanation of some of the non-English publications.

2. ☒ In accordance with 37 CFR § 1.98, a concise explanation of what is presently understood to be the relevance of each non-English language publication is

(Check appropriate Items 2a, 2b, 2c and/or 2d)

- 2a. ☐ satisfied because all non-English language publications were cited on the enclosed "English-language version of the search report or action which indicates the degree of relevance found by the foreign office". (See MPEP 609, Minimum Requirements for an Information Disclosure Statement, Part A(3): Concise Explanation of Relevance, pp. 600-100 to 600-101, Rev. 1, Feb. 2000.)
- 2b. ☐ set forth in the application.

- 2c. ☒ satisfied because an English language translation (Abstract Only) is attached to some of the non-English language publications.
- 2d. ☒ enclosed as Attachment 1(e), hereto for some of the non-English language publications.
3. No admission is made that the information cited in this Statement is, or is considered to be, material to patentability nor a representation that a search has been made (other than search report(s) from a counterpart foreign application or a PCT International Search Report, if submitted herewith). 37 CFR §§ 1.97(g) and (h).

Respectfully submitted,

STAAS & HALSEY LLP

Dated: 4/9/04

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FORM PTO-1449 <div style="text-align: center;">U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</div> <div style="text-align: center;"><b>LIST OF REFERENCES CITED BY APPLICANT</b></div> <div style="text-align: center;"><i>(Use several sheets if necessary)</i></div>	ATTORNEY DOCKET NO. 1572.1259	APPLICATION NO. Unassigned
FIRST NAMED INVENTOR Jon-rok PARK et al.		
FILING DATE April 9, 2004		GROUP ART UNIT Unassigned

### U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUB-CLASS	FILING DATE
AA	US2002/0130276A1	9/2002	Sogard			
AB						
AC						

### FOREIGN PATENT DOCUMENTS

DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION YES NO	
AD	2000-26856	Korea				X
AE	2001-46528	Korea				X
AF	10-316711	Korea				X
AG	10-313028	Korea				X
AH	10-303076	Korea				X
AI	P2002-305238A	Japan			abst	
AJ	7-249586	Japan			abst	
AK	1-251735	Japan			abst	
AL	2000-36490A	Japan			abst	

### OTHER REFERENCES (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

TRANSLATION YES NO
AM
AN
AO

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<b>EXPLANATIONS OF RELEVANCY OF REFERENCES</b>	ATTORNEY DOCKET NO. 1572.1259	APPLICATION NO. Unassigned
	FIRST NAMED INVENTOR Jon-rok PARK et al.	
	FILING DATE April 9, 2004	GROUP ART UNIT Unassigned

Korean Publication No. 2000-26856 issued May 15, 2000 relates to an electrostatic chuck for wafer.

Korean Publication No. 2001-46528 issued June 15, 2001 relates to an electrostatic chuck for wafer.

Korean Publication No. 10-316711 issued November 23, 2001 relates to an electrostatic chuck for wafer.

Korean Publication No. 10-313028 issued October 16, 2001 relates to an electrostatic chuck for wafer.

Korean Publication No. 10-303076 issued July 9, 2001 relates to an electrostatic chuck for wafer.